and receiving a plurality of inspection results, a data processor analyzing the inspection results from the process executor to determine a second sampling rate, a storage device storing the second sampling rate, and a controller receiving the second sampling rate from the storage device and changing the first sampling rate of the inspection requested by the process executor to the second sampling rate.--

IN THE SPECIFICATION:

Please add the following paragraph after the paragraph ending on page 3, line 6:

--Further scope of the applicability of the present invention will become apparent from the detailed description given hereinafter. However, it should be understood that the detailed description and specific examples, while indicating preferred embodiments of the invention, are given by way of illustration only, since various changes and modifications within the spirit and scope of the invention will become apparent to those skilled in the art from this detailed description.--

Please replace the paragraph beginning on page 3, line 9, with the following rewritten paragraph:

--The following detailed description, given by way of example and not intended to limit the invention solely to the embodiments

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described herein, will best be understood in conjunction with the accompanying drawings, which are given by way of illustration only, and thus are not limitative of the present invention, and in which:--

Please replace the paragraph beginning on page 3, line 20, with the following rewritten paragraph:

--FIG. 1 is a diagram showing a system for dynamically monitoring stability of manufacturing equipment according to one embodiment of the invention. A system 1 comprises a MES 11, a Statistical Process Control (SPC) database and analyzer (a software application) 12, a sampling rate database 13, an input device 131 and a display 132 connected to the sampling rate database 13, and a server 14.--